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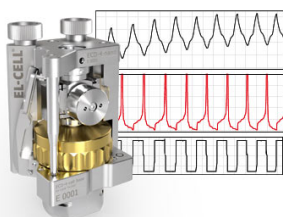
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Comparison of 10 MeV Neutron Irradiation Effects on NiO/Ga₂O₃ Heterojunction Rectifiers and Ni/Au/Ga₂O₃ Schottky Rectifiers

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Neutrons generated through charge-exchange ⁹Be (p; nⁱ) ⁹Be reactions, with energies ranging from 0–33 MeV and an average energy of ~9.8 MeV were used to irradiate conventional Schottky Ga₂O₃ rectifiers and NiO/Ga₂O₃ p-n heterojunction rectifiers to fluences of 1.1–2.2 × 10¹⁴ cm⁻². The breakdown voltage was improved after irradiation for the Schottky rectifiers but was highly degraded for their NiO/Ga₂O₃ counterparts. This may be a result of extended defect zones within the NiO. After irradiation, the switching characteristics were degraded and irradiated samples of both types could not survive switching above 0.7 A or 400 V, whereas reference samples were robust to 1 A and 1 kV. The carrier removal rate in both types of devices was ~45 cm⁻¹. The forward currents and on-state resistances were only slightly degraded by neutron irradiation.

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There is significant recent interest in Ga₂O₃-based rectifiers for power inversion applications because of their lower switching losses and higher breakdown voltages compared to SiC and GaN.^{1–12} A recent advance has also come from the use of p-NiO/n-Ga₂O₃ heterojunction rectifiers to overcome the absence of a native p-type doping capability in Ga₂O₃.^{13–33} While excellent dc and switching performance has been reported from these devices, there is little information on their response to radiation. One of the most common forms of radiation encountered by semiconductor devices is neutron irradiation.^{34–37} Neutrons create primary knock-on displaced atoms in semiconductors, which produce trap states in the bandgap and degrade the electrical properties. The main mechanism for producing these displaced atoms is elastic and inelastic collisions between the incoming neutron and nuclei in the crystalline semiconductor.³⁷ If a high enough energy is transferred, there may also be further displacements, producing a cascade of defects. There is also the possibility of atomic displacement due to neutron capture interaction and related nuclear reactions. These defects cause trap states mostly created by non-ionizing energy-loss (NIEL) processes,^{38,39} which generate primary defects by the initial particle interaction and by the cascade generation due to nucleus recoil, and secondary defects caused by the diffusion of the primary point defects.⁴⁰ For fast neutrons which create large recoil cascades, carrier removal is by disordered regions in which the Fermi level in the core is pinned.

There are numerous applications where neutron exposure to neutron fluxes may occur, including nuclear reactors or simply terrestrial neutron showers due to interactions of high-energy primary cosmic rays with gases in the upper atmosphere.^{36,37} This flux increases at lower altitude due to a higher number of cosmic ray-gas and neutron-gas interactions. The maximum flux is ~1 n cm⁻²s at 20 km altitude. The terrestrial neutron flux decreases at lower altitudes due to scattering and decreased cosmic ray energy. The energy per cm³ deposited through atomic displacements by neutrons is characterized by the spectral fluence $\phi(E)$ in units of n/cm² MeV.^{36,37}

The amount of non-ionizing energy loss varies greatly for different types of radiation, as shown in Fig. 1 for β -Ga₂O₃. Here we have calculated the NIEL for a typical fast heavy ion, Au, as well as protons, electrons, alpha particles and neutrons.³⁸ While neutrons are the least damaging from this regard, their ubiquity in the

environment means there is a need to understand their effects on Ga₂O₃-based devices.^{41–45}

In this paper, we report a comparison of 10 MeV neutron irradiation of NiO/Ga₂O₃ heterojunction rectifiers with conventional Schottky Ga₂O₃ rectifiers. We find no significant difference in the response of the two types of rectifiers to neutron irradiation, and a high degree of robustness against neutron damage in both cases.

Experimental

The common epitaxial layer structure for both Schottky and heterojunction rectifiers consisted of 8 μ m thick halide vapor phase epitaxy (HVPE) layer (2 × 10¹⁶ cm⁻³) grown by (001) n⁺ β -Ga₂O₃ substrate (Novel Crystal Technology, Japan). A full-area backside Ti/Au Ohmic contact was deposited by e-beam evaporation and annealed at 550 °C for 60 s under N₂.³⁰ For the heterojunction rectifiers we deposited a bilayer NiO structure by magnetron sputtering (3 mTorr, 150 W, 13.56 MHz). The carrier concentration in the bilayer (10 nm/10 nm) structure was controlled by the Ar/O₂ ratio during sputtering at levels of 2 × 10¹⁸–3 × 10¹⁹ cm⁻³. The structures were completed with Ni/Au (200–1000 μ m diameter) deposited onto either the NiO layer in the case of the heterojunction devices or the bare Ga₂O₃ in the case of the Schottky rectifiers. Figure 2 shows schematics of both device structures.

The neutron irradiation was performed at the Korea Institute of Radiological and Medical Science with a 45 MeV MC-50 cyclotron. 35 MeV protons colliding with beryllium elements generated neutrons by nuclear reactions. The beam passes through two Al degrader films before hitting the Be target. Production of energetic neutrons is dominated by charge-exchange ⁹Be (p; nⁱ) ⁹Be reactions. The proton to neutron generation ratio was approximately 8200:1. The average energy of the generated neutrons was 9.8 MeV, as shown in the spectrum of Fig. 3. The devices were irradiated for 2 or 4 h with the total fluence of 1.1 × 10¹⁴ or 2.2 × 10¹⁴ cm⁻² of neutrons at room temperature. The rectifiers were not under bias during the neutron irradiation.

The current-voltage (I–V) characteristics were recorded with a Tektronix 370-A curve tracer, 371-B curve tracer and Agilent 4156C was used for forward and reverse current measurements. The capacitance-voltage (C–V) measurements were made on the parameter analyzer. The reverse recovery was measured on a pulse generator.

Results and Discussion

The C–V data was plotted in the form C⁻²–V in Fig. 4 to extract the carrier concentration before and after the neutron

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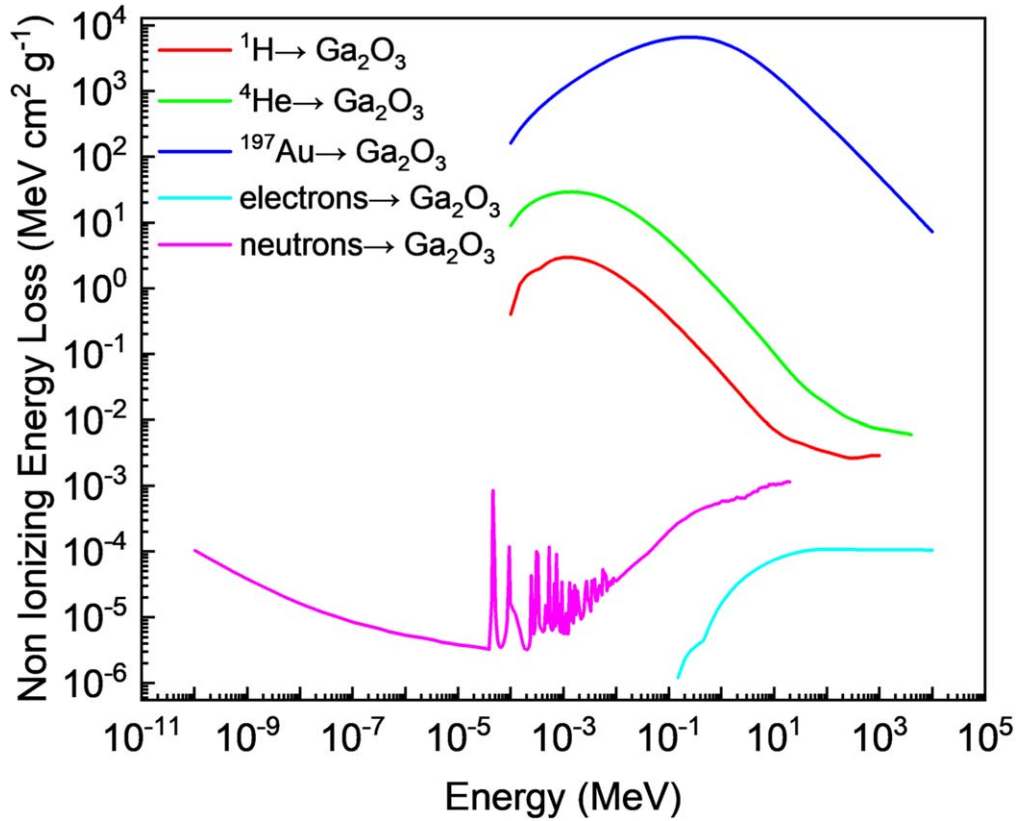


Figure 1. NIEL loss as a function of energy for protons, alpha particles, a typical heavy ion (Au), electrons and neutrons in Ga₂O₃.

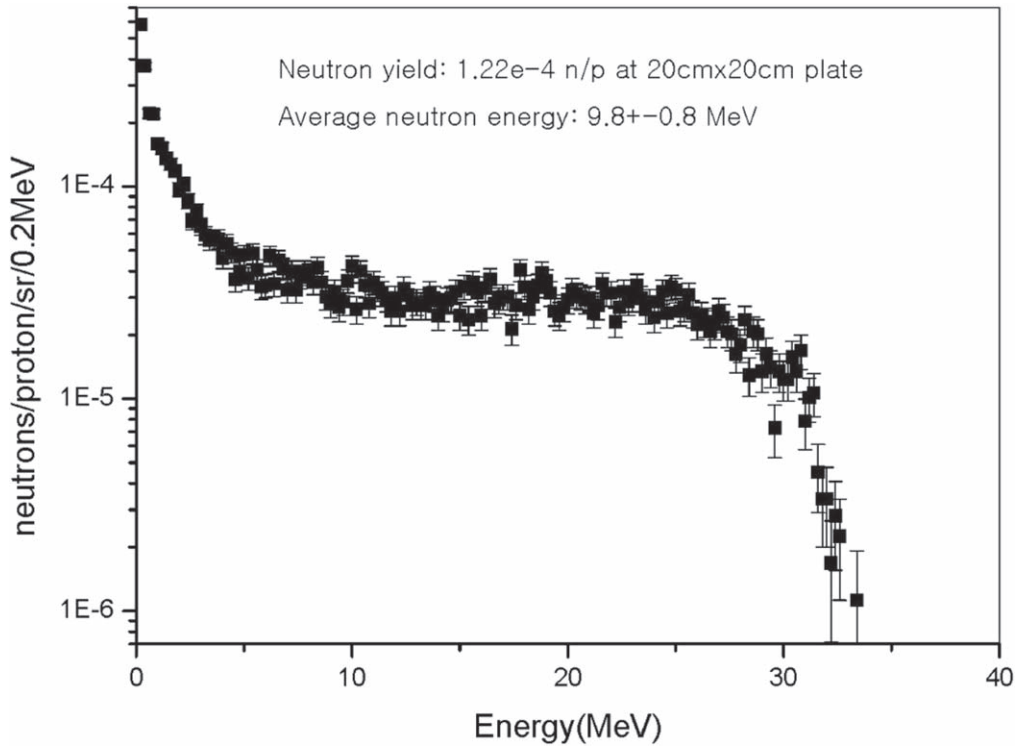


Figure 2. Neutron/proton yield as a function of energy from the irradiation source used in these experiments.

irradiation of both types of devices. These are expected to be similar since the depletion in the both the p-n heterojunctions and the Schottky rectifier will be in the n-Ga₂O₃. As tabulated in

Table I, the carrier concentration is slightly reduced after neutron irradiation, with an approximate carrier removal rate, R_C , defined by^{44,45}

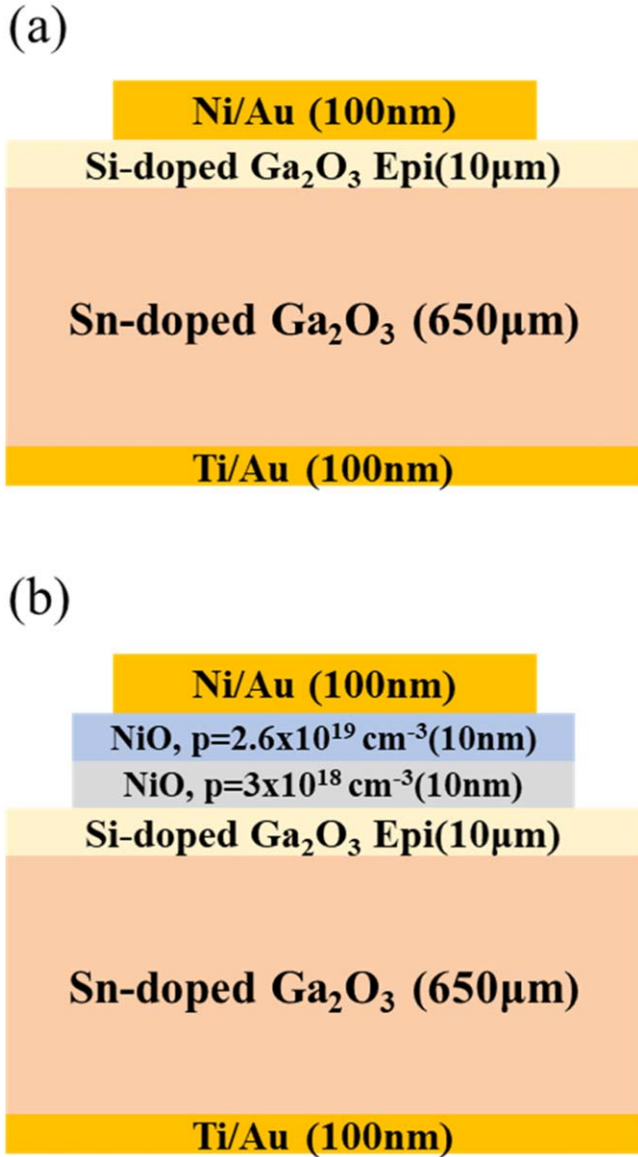


Figure 3. Schematic of the (a) Ga₂O₃ Schottky rectifiers and (b) NiO/Ga₂O₃ heterojunction rectifiers.

Table I. Summary of changes in electrical properties of Schottky and heterojunction NiO/Ga₂O₃ rectifiers as a result of neutron irradiation at two different doses. N_D is the drift region carrier concentration, W_n is the depletion width and V_{bi} is the built-in bias.

Sample	N_D (Ga ₂ O ₃) (cm ⁻³)	W_n (nm)	V_{bi} (V)
Ga ₂ O ₃ ref	2.1×10^{16}	236	1.05
1.1×10^{14}	1.1×10^{16}	382	1.43
2.2×10^{14}	1.05×10^{16}	397	1.49
NiO/Ga ₂ O ₃ ref	2.1×10^{16}	240	2.09
1.1×10^{14}	2.0×10^{16}	247	2.7
2.2×10^{14}	1.5×10^{16}	290	253

$$R_C = (n_{s0} - n_s)/\Phi$$

where Φ is the neutron fluence, n_{s0} is initial carrier concentration, and n_s is the irradiated carrier concentration. The R_C value was

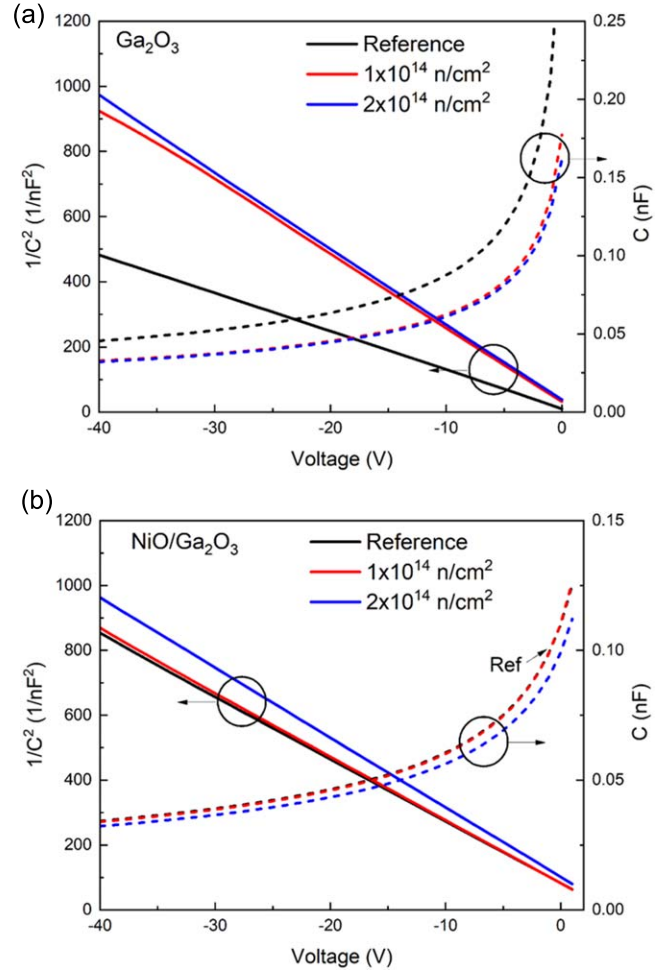


Figure 4. C^{-2} - V characteristics from (top) Schottky Ga₂O₃ rectifiers and (bottom) NiO/Ga₂O₃ heterojunction rectifiers before and after neutron irradiation.

$\sim 45 \text{ cm}^{-1}$, which is broadly consistent with reported values for neutrons with similar or lower energies, given the large uncertainties in some cases of this parameter. Farzana et al.⁴⁰ reported a removal rate of $\sim 51 \text{ cm}^{-1}$ for n-Ga₂O₃ irradiated with reactor neutrons with energy spread ~ 1 –20 MeV. Lee et al.⁴⁵ reported a removal rate of $\sim 480 \text{ cm}^{-1}$ for neutrons of average energy 4.2 MeV from a ²⁴¹Am-Be source, with energy spread 1–11 MeV. The removal rates in β -Ga₂O₃ for neutrons are on par with those reported for n-GaN and n-SiC.^{40,44–46}

Figure 5 shows the forward I-V characteristics from the two types of devices. There are only minor reductions in forward current and increase in on-state resistance, R_{ON} , because of the neutron irradiation. Table I also shows only relatively minor increases in the built-in voltage of the Schottky and p-n junctions. This is not too unexpected since the NiO is highly conducting and should not be affected much by the neutrons,³⁰ which have a long mean free path in Ga₂O₃ of $>10 \text{ cm}$. This is obviously much larger than the total sample thickness of the samples. The scattering cross section of neutrons in NiO is $<0.5 \text{ cm}^{-1}$ indicates the average number of interactions per neutron is of order 2×10^5 reactions/cm² for the NiO region of the rectifier structure 2000 times higher for the depletion region at the highest dose condition.

Figure 6 shows the reverse I-V characteristics at low biases, with little change in reverse current for either type of rectifier. However, there was a significant effect on reverse breakdown voltage, as shown in Fig. 7 and tabulated in Table I. The first thing to note is the

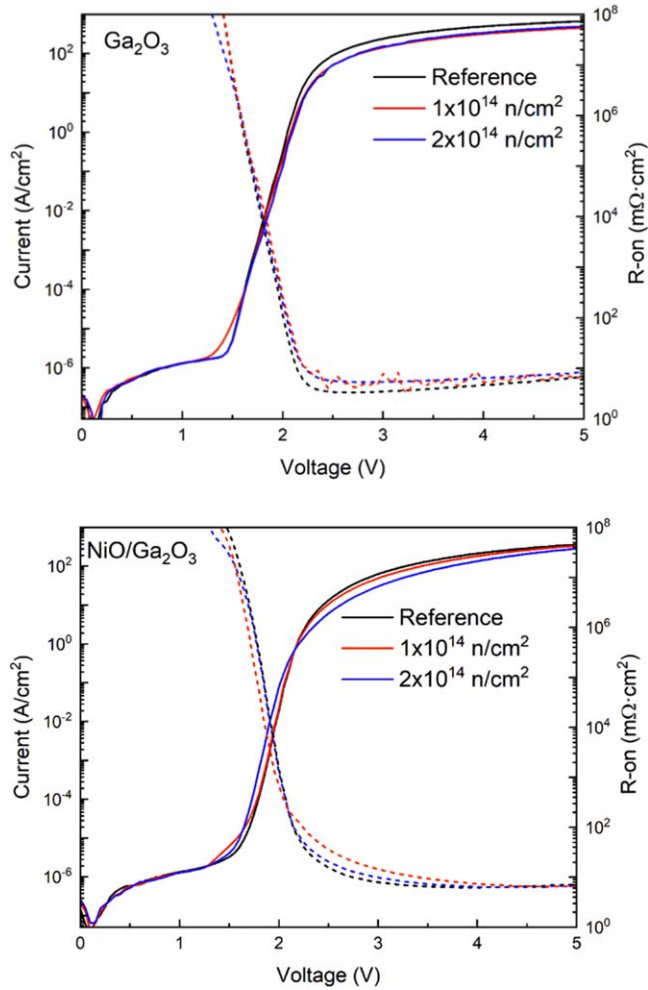


Figure 5. Forward I-V and on-state resistance characteristics from (top) Schottky Ga_2O_3 rectifiers and (bottom) $\text{NiO}/\text{Ga}_2\text{O}_3$ heterojunction rectifiers before and after neutron irradiation.

Table II. Summary of switching performance of Schottky and heterojunction $\text{NiO}/\text{Ga}_2\text{O}_3$ rectifiers before and after neutron irradiation. T_{rr} is the reverse recovery time, I_{rr} the reverse recovery current, dI/dt is the rate of current during the switching and I_F the forward current at 10 V.

Sample	T_{rr} (ns)	I_{rr} (mA)	dI/dt (A/ μ s)	I_F (mA)
Ga_2O_3 ref	29.7	-50	4.5	122
1.1×10^{14}	28.1	-47	4.4	109
2.2×10^{14}	26.4	-41	4.2	109
$\text{NiO}/\text{Ga}_2\text{O}_3$ ref	27.6	-45	4.2	97
1.1×10^{14}	27.6	-46	4.1	91
2.2×10^{14}	27.8	-46	3.9	84

large increase in V_B when the NiO is used as the cathode contact relative to the Schottky metal on the same epitaxial layer structure. This has been noted by numerous authors and emphasizes also that the NiO provides excellent edge termination. The V_B increased after irradiation for the Schottky rectifiers, from 884 V for the reference to 1.2 kV for the highest neutron dose. By sharp contrast, the V_B for the $\text{NiO}/\text{Ga}_2\text{O}_3$ showed a sharp decrease upon neutron irradiation, from 3.96 kV in the reference to 1.32 kV in the highest dose device. The increase in the conventional Schottky rectifier might be ascribed to

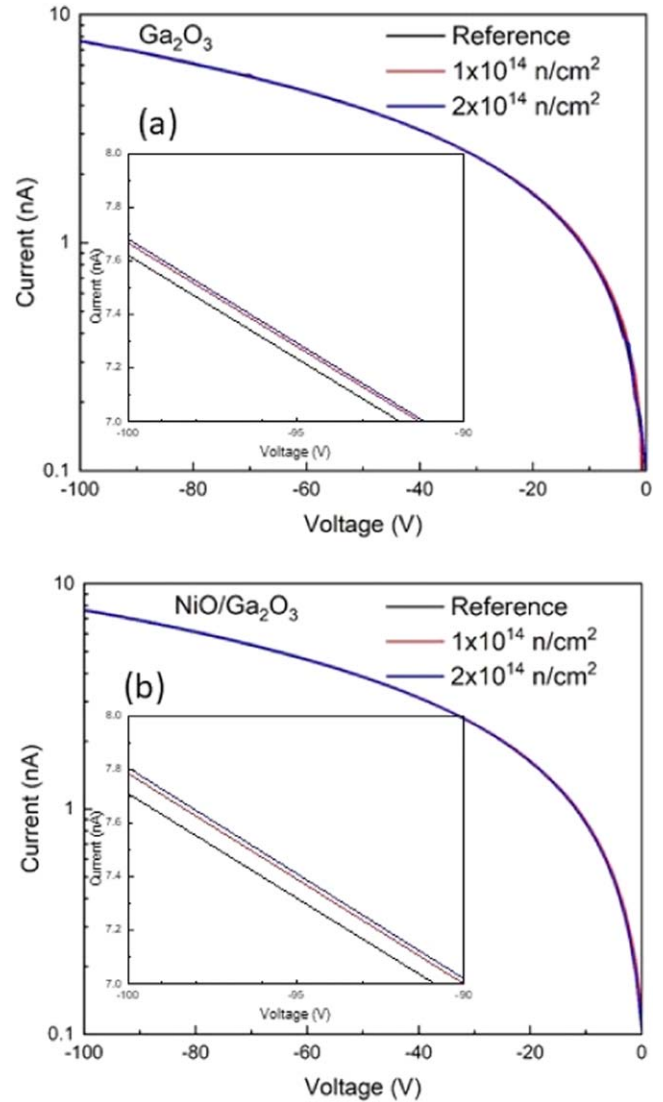


Figure 6. Reverse I-V characteristics at low bias from (top) Schottky Ga_2O_3 rectifiers and (bottom) $\text{NiO}/\text{Ga}_2\text{O}_3$ heterojunction rectifiers before and after neutron irradiation. The insets show the differences arising from the neutron irradiation.

the small decrease in effective carrier concentration in the drift region. If this were the only effect present, then the V_B of the NiO devices should also increase. The large degradation in V_B in those devices indicated there is a change in the NiO itself, since the breakdown voltages trend back towards those of the Schottky rectifiers. Note that the reverse current is suppressed compared to the reference up to the point of breakdown. This may indicate creation of disordered regions (Gossick zones)^{43,47-49} within the NiO because of neutron irradiation. We plan to examine single layers of NiO by high resolution electron microscopy to try to directly observe if such damage zones are present.

Figure 8 shows the reverse recovery characteristics before and after neutron irradiation for both types of rectifiers. The measurement circuit condition was switching the bias from +10 to -10 V for a period of 10 μ s (duty cycle 20%) and switching period of 50 μ s. Table II summarizes the resultant reverse recovery time constants, T_{rr} , defined as the time required to reach 25% of the peak current, as well as the I_{rr} and rate of change of current, dI/dt (A/ μ s). The changes in these parameters after irradiation are relatively small in all cases.

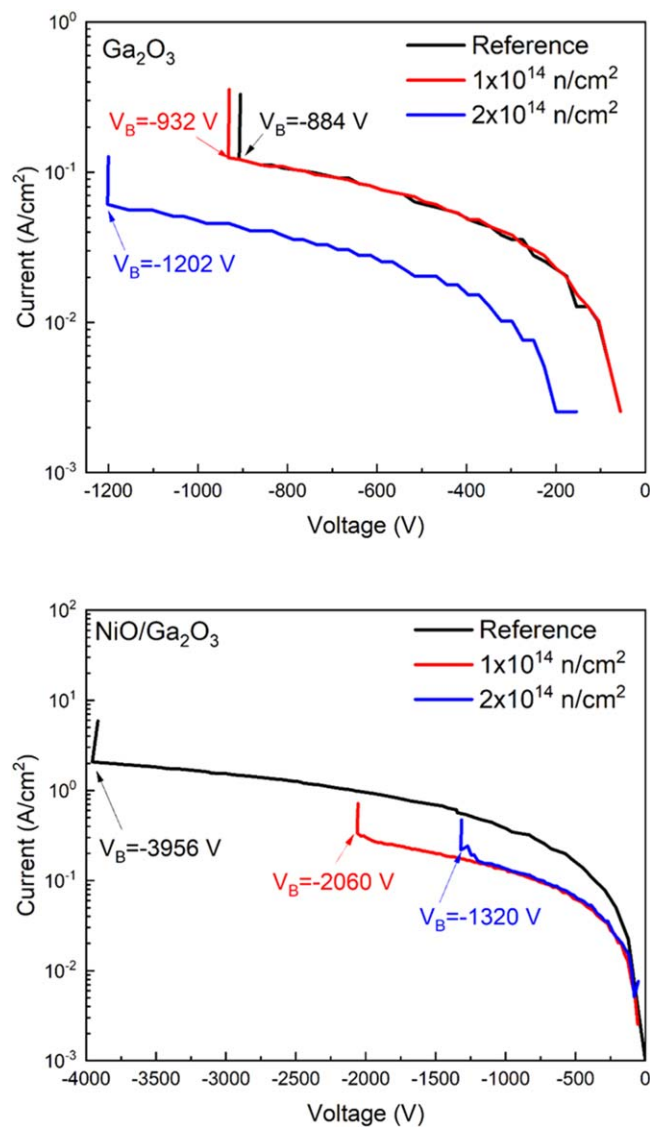


Figure 7. Reverse I-V characteristics from (top) Schottky Ga₂O₃ rectifiers and (bottom) NiO/Ga₂O₃ heterojunction rectifiers before and after neutron irradiation. The breakdown voltages are indicated in each case.

Summary and Conclusions

In summary, a comparison of the effects of neutron irradiation on conventional Schottky Ga₂O₃ rectifiers and NiO/Ga₂O₃ p-n heterojunction rectifiers shows that neutron irradiation had contrasting effects on the reverse breakdown voltage of these devices. Neutron irradiation of Schottky and p-n heterojunction Ga₂O₃ rectifiers shows major differences in the effect on reverse breakdown voltage. In the case of conventional Schottky rectifiers, the reverse breakdown voltage increases with neutron dose, due to a decrease in the effective carrier concentration in the drift region.⁴⁹ By sharp contrast, NiO/Ga₂O₃ heterojunction rectifiers fabricated on the same epitaxial layer structures show significant decreases in reverse breakdown voltage because of the same neutron irradiations. There was little difference in the forward or low-bias reverse currents between the two structures and little significant change in reverse recovery characteristics. Additional characterization and simulations to support our hypothesis are planned to provide a more comprehensive understanding of the observed behavior. This will provide more insight into the potential implications of the observed differences in reverse breakdown voltage on the overall performance

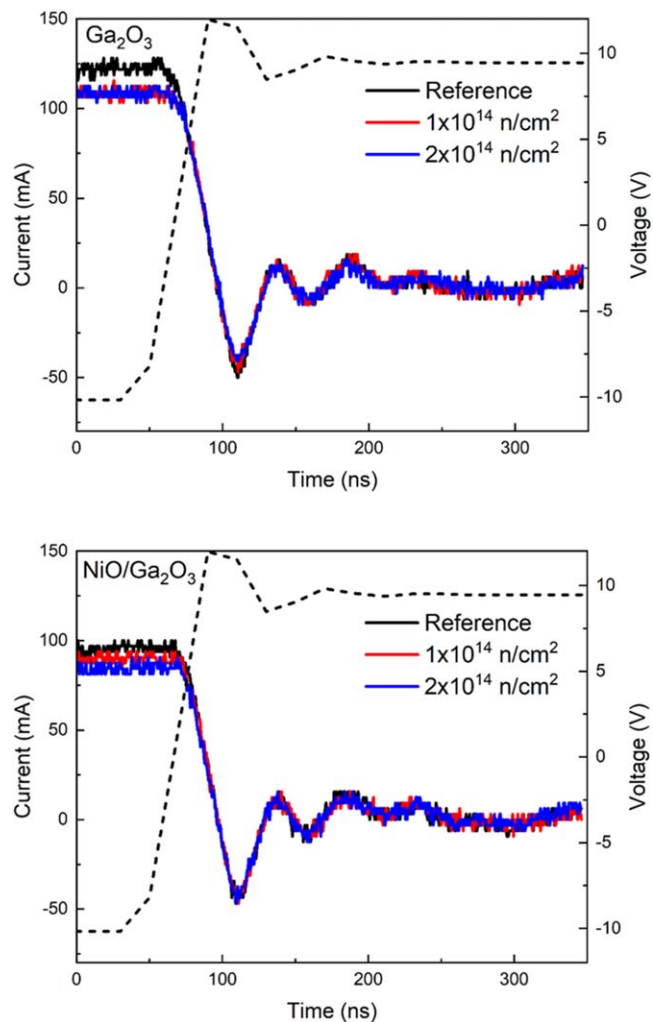


Figure 8. Switching characteristics from (top) Schottky Ga₂O₃ rectifiers and (bottom) NiO/Ga₂O₃ heterojunction rectifiers before and after neutron irradiation, measured under pulsed conditions (Period = 50 μ S, Duty Cycle = 1 μ S (20%) Power Supply = +10/-10 V).

and reliability of the rectifiers, since these will affect considerations of device applications, limitations, and possible mitigation strategies to enhance the radiation hardness of the NiO/Ga₂O₃ heterojunction rectifiers. While the use of NiO to produce a p-n junction has a major beneficial effect on improving breakdown voltage in vertical geometry Ga₂O₃ rectifiers, it brings disadvantages in terms of the radiation hardness of the devices.

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Declarations

The authors have no conflicts to disclose.

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